

**Docket No.: 4425-320**

**PATENT**

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Application of	:
	: EXPEDITED PROCEDURE
Chien-Hsin LAI <i>et al.</i>	: Response under 37 CFR 1.116
	:
U.S. Patent Application No. 10/659,258	: Confirmation No. 3535
	: Group Art Unit: 1763
Filed: September 11, 2003	: Examiner: Karla A Moore

**For: PLASMA APPARATUS AND METHOD CAPABLE OF ADAPTIVE  
IMPEDANCE MATCHING**

Commissioner for Patents  
P. O. Box 1450  
Alexandria VA 22313-1450

**AMENDMENT**

Sir:

In response to the Office Action of May 18, 2006 please amend the above-identified application as follows: